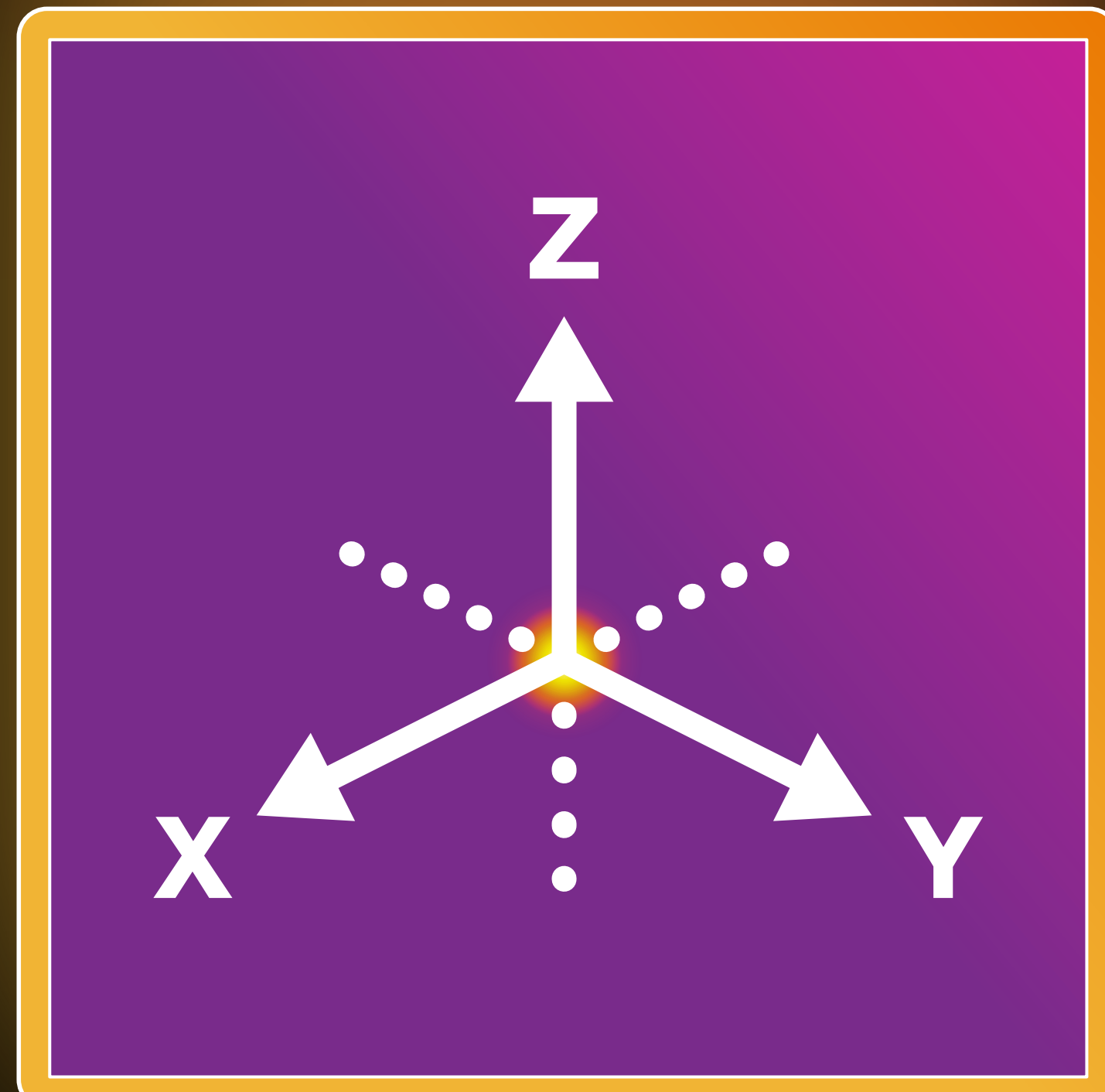


Accurately locate thermal failures

ThermoFisher
SCIENTIFIC

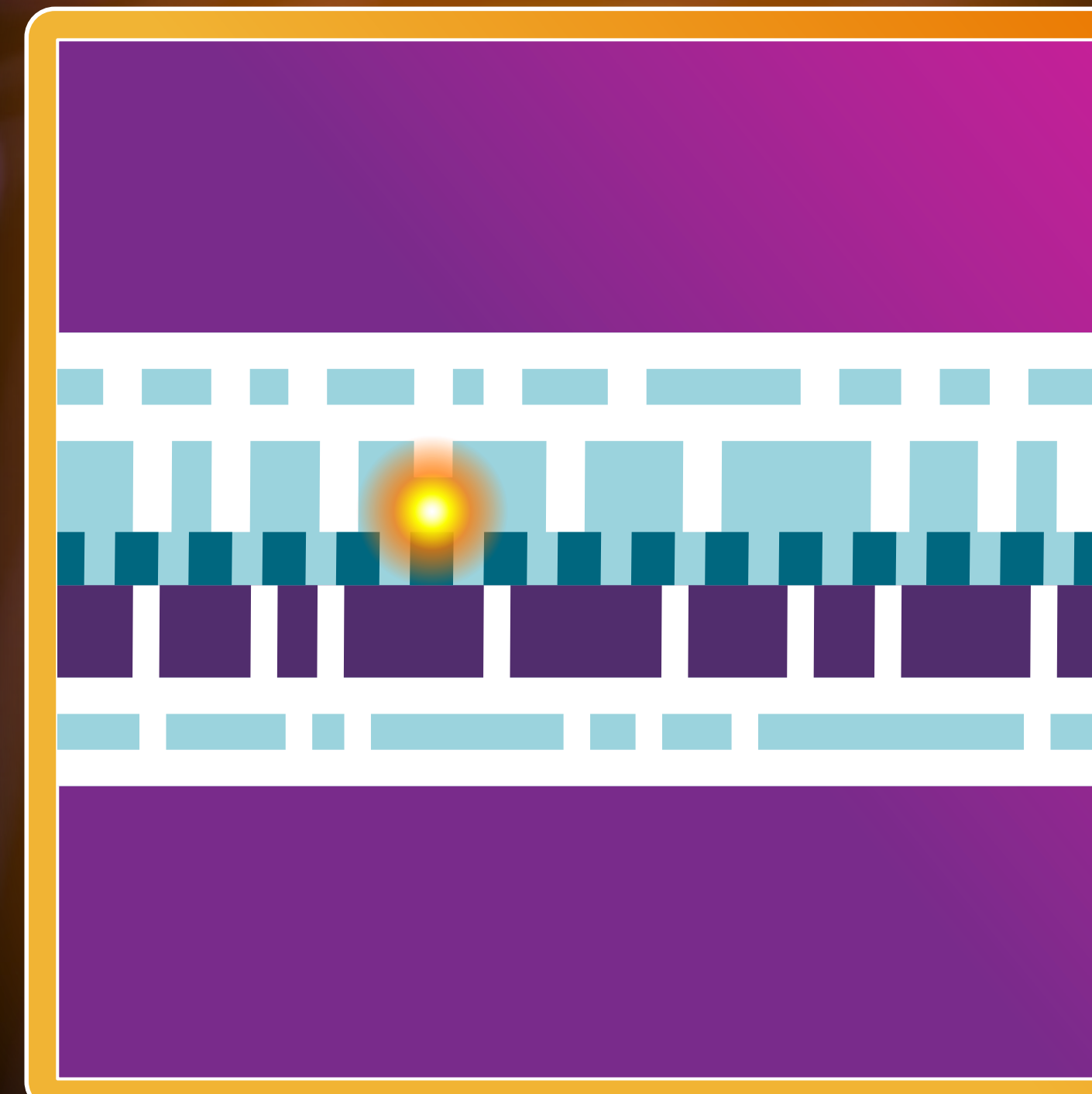
Semiconductor devices can fail for many reasons, leading to wasted time and increased costs. The Thermo Scientific[™] ELITE[™] System's infrared (IR) lock-in thermography (LIT) offers the signal-to-noise ratio, sensitivity, and feature resolution you need to detect the temperature variations that lead to device failures.

Precise fault localization



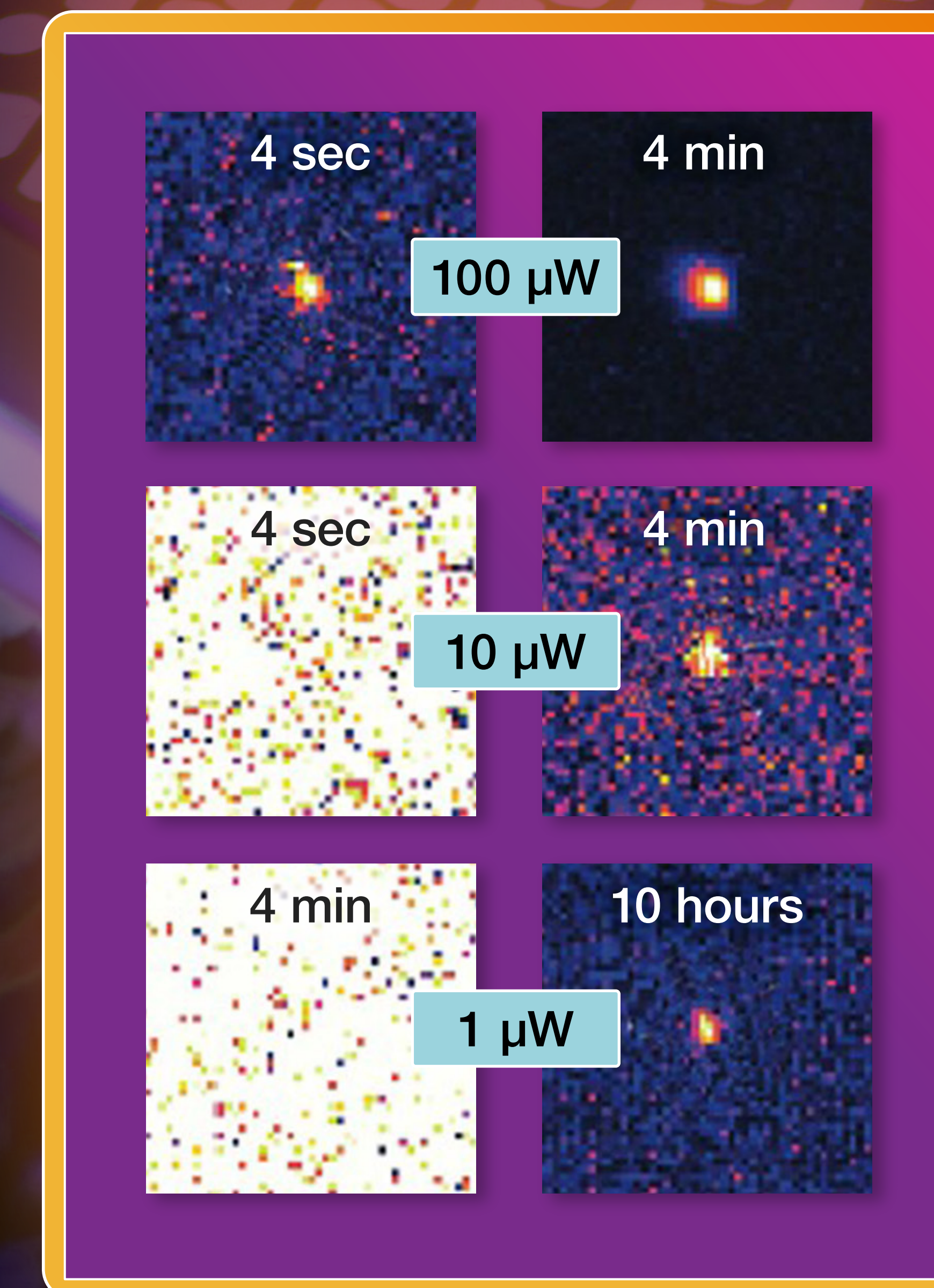
The ELITE System's improved sensitivity leads to easier defect detection and identification, resulting in more precise localization to kick off your FA workflow.

Detect defects at any level



The ability to locate a thermal source in three dimensions makes the ELITE System well-suited for stacked-die analysis.

Lock-in thermography



Thermal images produced by the ELITE System, showing the power of lock-in technology for scaling acquisition time based on signal strength. Quickly go from millimeter-scale area to micron-scale defect.

Learn more at thermofisher.com/elite

thermo scientific